



DT07 Rec'd PCT/PTO 2 5 OCT 2004 PCT

PATENT

IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

Applicant: Androula G. Nassiopoulou )

Serial No.: 10/502,465 )

Filed: January 16, 2003 )


For: LOW POWER SILICON  
THERMAL SENSORS AND  
MICROFLUIDIC DEVICES BASED  
ON THE USE OF POROUS SEALED  
AIR CAVITY TECHNOLOGY OR  
MICROCHANNEL TECHNOLOGY )

Group Art Unit: To be assigned )

Examiner: To be assigned )

I hereby certify that this paper is being  
deposited with the United States Postal  
Service, first class postage prepaid, addressed  
to: Commissioner for Patents, P.O. Box 1450,  
Alexandria, VA 22313-1450

October 21, 2004

  
James P. Zeller  
Reg. No. 28,491

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:


Submitted herewith for consideration by the examiner are copies of the documents  
identified on the attached Form PTO-1449.

Entry and consideration of the submitted documents are solicited.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

October 21, 2004

By:   
James P. Zeller  
Reg. No. 28,491  
Attorneys for Applicants

6300 Sears Tower  
233 South Wacker Drive  
Chicago, Illinois 60606-6357  
(312) 474-6300



U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No.	Serial No.
	30848/40323	10/502,465
	Applicant	
	Androula G. Nassiopoulou	
Filing Date		Group
1/16/03		

**INFORMATION DISCLOSURE STATEMENT****U.S. PATENT DOCUMENTS**

*Examiner Initials	Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate
	6,359,276 B1	03/19/02	Tu	250	338.1	07/06/99

**FOREIGN PATENT DOCUMENTS**

*Examiner Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
						Yes	No
	1,251,945	05/03/00	China			Abstract only	
	WO 98/50763	11/12/98	PCT				

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)**

	"Porous Silicon Bulk Micromachining for Thermally Isolated Membrane Formation", Dűcső et al., Sensors and Actuators, A 60, 1997, pp. 235-239
	"Micromachined Silicon Thermopile and Thermal Radiators Using Porous Silicon Technology", Dobrzański et al., IEE Proc.-Optoelectron, Vol. 145, No. 5, October 1998, pp. 307-311
	"Frontside Bulk Silicon Micromachining Using Porous-Silicon Technology", Kaltsas et al., Sensors and Actuators A 65, 1998, pp. 175-179
	"Novel C-MOS Compatible Monolithic Silicon Gas Flow Sensor with Porous Silicon Thermal Isolation", Kaltsas et al., Sensors and Actuators 76, 1999, pp. 133-138
	"Permeated Porous Silicon for Hydrocarbon Sensor Fabrication", Angelucci et al., Sensors and Actuators 74, 1999, pp. 95-99
	"Free-Standing, Mobile 3D Porous Silicon Microstructures", Lammel et al., Sensors and Actuators 85, 2000, pp. 356-360
	"Porous Silicon as an Effective Material for Thermal Isolation on Bulk Crystalline Silicon", Nassiopoulou et al., Phys. Stat. Sol. (a) 182, 2000, pp. 307-311
	"Multi-Walled Microchannels: Free-Standing Porous Silicon Membranes for Use in $\mu$ TAS", Tjerkstra et al., Journal of Microelectromechanical Systems, Vol. 9, No. 4, December 2000, pp. 495-501
	International Search Report in PCT/GR03/00003 dated April 23, 2003

Examiner	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	